

5/5

**INSPECTING DEVICE**

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**Abstract**

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PURPOSE: To prevent possible erroneous decision, by irradiating an object to be inspected with an S polarized light and P polarized light while the P polarized light component alone is detected among the lights reflected on the object being inspected.

CONSTITUTION: When a P polarized light and an S polarized light is made to irradiate a defect on a wafer 1 from laser light sources 4 and 5 of an illuminator 3, the P polarized light component is contained in the reflected light thereof. The P polarized light component is detected intensely with a photo detector 8 as transmitted through a polarization plate 7. This causes a very large difference in the level between the signal involved in the detection of the defect and the signal done in the detection of a pattern and thus, almost eliminate the possibility of erroneous decision overlooking the defect regardless of relax of the threshold in the detection of a defect by comparing two pellets.

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